(0-728,909 SHEET /1 OF 1

INFORMATION DISCLOSURE CITATION PTO-1449				ATTORNEY'S DKT NO. H1124			APPLICATION NO.			
			Customer Number		APPLICANT(s) Cyrus E. Tabery et al.					
			26615	Ì	FILING DATE December 8, 2003		GROUP  GROUP  GROUP  GROUP  GROUP			
									63	
U.S. PATENT DOCUMENTS										
EXAMINER'S INITIALS PATENT NO. DATE			NA.	NAME		CLASS	SUBCLASS	FILING DATE		
			- IVAINE			OBAGO	JOBELAGO		``-	
									_	
			****		<del></del>					
			ICAI DATENT O	-	NIMENTO		<u> </u>			
EXAMINER'S		PURE	EIGN PATENT DOCUMENTS				Translation			
INITIALS	PATENT NO. DATE	:	cou	NTI	RY	CLASS	SUBCLASS	Yes	No	
									<u> </u>	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  Digh Hisamoto et al., "FinFET-A Self-Aligned Double-Gate MOSFET Scalable to 20 nm,"										
IEEE Transactions on Electron Devices, Vol. 47, No. 12, December 2000, pages 2320-2325.										
0 0	Yang-Kyu Choi et al., "Sub-20nm CMOS FinFET Technologies," 2001 IEEE, IEDM, pages 421-424.									
Xuejue Huang et al., "Sub-50 nm P-Channel FinFET," IEEE Transactions on Electron Devices, Vol. 48, No. 5, May 2001, pages 880-886.										
Xuejue Huang et al., "Sub 50-nm FinFET: PMOS," 1999 IEEE, IEDM, pages 67-70.										
Yang-Kyu Choi et al., "Nanoscale CMOS Spacer FinFET for the Terabit Era," IEEE Electron Device Letters, Vol. 23, No. 1, January 2002, pages 25-27.										
EXAMINER George Goudrean DATE CONSIDERED 7-051										

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).